Top-left panel (egx50—5a):
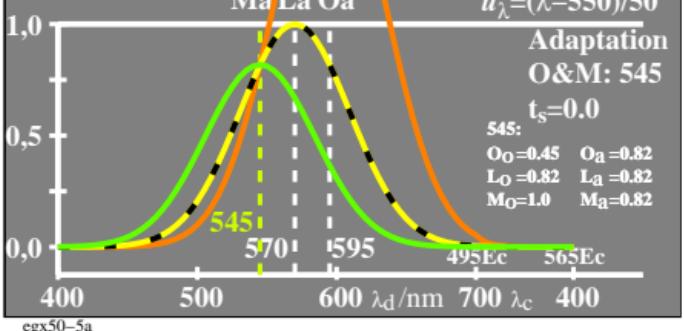
lin[Empfindlichkeit]

$\log L_o = -0.35[u_\lambda - u_{570}]^2$

$\log O_o = -0.35[u_\lambda - u_{595}]^2$

$\log M_o = -0.35[u_\lambda - u_{545}]^2$

$\log L_a = \log L_o + 0.00$

$\log O_a = \log O_o + 0.26$

$[L_o, O_o, M_o]$

$\log M_a = \log M_o - 0.09$

$u_\lambda = (\lambda - 550)/50$

Ma La Oa

Adaptation

O&M: 545

$t_s = 0.0$

545:

$O_O = 0.45$ $O_a = 0.82$

$L_O = 0.82$ $L_a = 0.82$

$M_O = 1.0$ $M_a = 0.82$

1,0   0,5   0,0

545

570   595   495Ec   565Ec

400   500   600   700 λ_d/nm λ_c

egx50—5a

Top-right panel (egx50—6a):
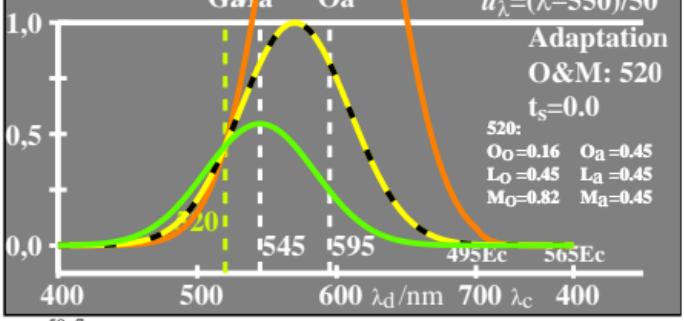
lin[Sättigung]

$\log O_o = -0.35[u_\lambda - u_{595}]^2$

$\log L_o = -0.35[u_\lambda - u_{570}]^2$

$\log M_o = -0.35[u_\lambda - u_{545}]^2$

$\log L_a = \log L_o + 0.00$

$\log O_a = \log O_o + 0.26$

$[L_o/L_o, O_o/L_o, M_o/L_o]$

$\log M_a = \log M_o - 0.09$

Ma La Oa

Sättigung L

Adaptation

O&M: 545

$t_s = 0.0$

2   0   -2

545

570   595   495Ec   565Ec

400   500   600   700 λ_d/nm λ_c 400

egx50—6a

Bottom-left panel (egx50—7a):

lin[Empfindlichkeit]

$\log O_o = -0.35[u_\lambda - u_{595}]^2$
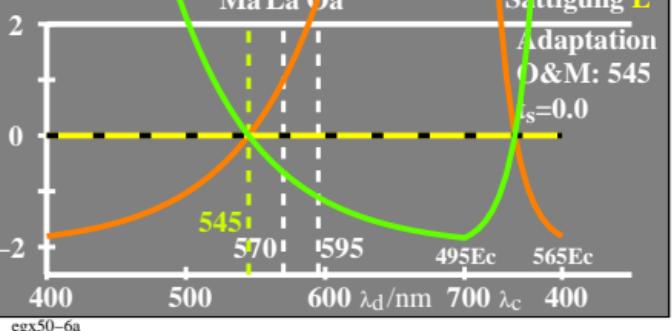
$\log L_o = -0.35[u_\lambda - u_{570}]^2$

$\log M_o = -0.35[u_\lambda - u_{545}]^2$

$\log L_a = \log L_o + 0.00$

$\log O_a = \log O_o + 0.44$

$[L_o, O_o, M_o]$

$\log M_a = \log M_o - 0.26$

$u_\lambda = (\lambda - 550)/50$

GMa   Oa

Adaptation

O&M: 520

$t_s = 0.0$

520:

$O_O = 0.16$ $O_a = 0.45$

$L_O = 0.45$ $L_a = 0.45$

$M_O = 0.82$ $M_a = 0.45$

1,0   0,5   0,0

520

545   595   495Ec   565Ec

400   500   600   700 λ_d/nm λ_c

egx50—7a

Bottom-right panel (egx50—8a):

lin[Sättigung]

$\log O_o = -0.35[u_\lambda - u_{595}]^2$

$\log L_o = -0.35[u_\lambda - u_{570}]^2$

$\log M_o = -0.35[u_\lambda - u_{545}]^2$

$\log L_a = \log L_o + 0.00$

$\log O_a = \log O_o + 0.44$

$[L_o/L_o, O_o/L_o, M_o/L_o]$

$\log M_a = \log M_o - 0.26$

GMa   Oa

Sättigung L

Adaptation

O&M: 520

$t_s = 0.0$

2   0   -2

520

545   595   495Ec   565Ec

400   500   600   700 λ_d/nm λ_c 400

egx50—8a

egx50—7n